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PATENT

IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE

Applicant: Young-Soo Kim

Serial No.: 10/615,038

Filed: July 8, 2003

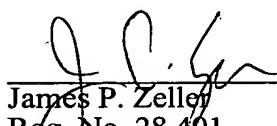
For: ATOMIC LAYER
DEPOSITION OF TITANIUM
NITRIDE USING BATCH TYPE
CHAMBER AND METHOD FOR
FABRICATING CAPACITOR BY
USING THE SAME

Group Art Unit: 2891

Examiner: Bradley Smith

I hereby certify that this paper (or fee) is being deposited with the United States Postal Service, first class postage prepaid, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

March 6, 2006



James P. Zeller
Reg. No. 28,491

RESPONSE TO OFFICIAL ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is in response to the official action of March 1, 2006, forwarding an interview summary summarizing the results of a telephonic interview conducted February 1, 2006, between the undersigned and Examiner Smith.

The interview summary states as follows:

"The examiner and the attorney for the application discussed the initial allowance of claims 7 and subsequent cancellation of claim 7. The examiner allowed claim 7 in error and subsequently canceled claim 7 in an office action filed on 1/12/0[6]. Furthermore, it was understood that claim 7 would be filed in a divisional application."

Applicant's undersigned attorney hereby confirms the accuracy and completeness of the examiner's interview summary.

This application was allowed, and the issue fee was paid October 12, 2005. Prompt issuance of a patent is solicited.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP

By:


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March 6, 2006

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